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Attorney Docket No. TT4314

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Christopher L. Wooten, et al. : Group Art Unit: 2623  
Appl. No.: 09/976,739 : Examiner: Wesley J. Tucker  
Filed: October 11, 2001 :  
Title: METHOD FOR EVALUATING ANOMALIES IN A SEMICONDUCTOR  
MANUFACTURING PROCESS

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Attached hereto is a completed Form PTO-1449 listing patents, publications, or other information which the applicant believes may be material to the examination of this application, with copies of each publication that is not an issued U.S. patent or U.S. patent publication and the first page of each issued U.S. patent and U.S. patent publication enclosed herewith. It is requested that the cited patents be made of record in the examination of this application. No item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application, and, to the knowledge of the person signing the certification after making reasonable inquiry, no item of information contained in the information disclosure statement was known to any individual designated in § 1.56(c) more than three months prior to the filing of the information disclosure statement.

Respectfully submitted,

Dated: 29 July 2005 By Rennie Wm. Dover  
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**CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8**

I hereby certify that this document (and any as referred to as being attached or enclosed) is being deposited with sufficient postage as first class mail with the United States Postal Service on July 29, 2005 and addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code, and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

Callen JB



<b>FORM PTO-1449</b> <b>U.S. DEPARTMENT OF COMMERCE</b> <b>PATENT AND TRADEMARK OFFICE</b>  <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (Use several sheets if necessary)	<b>ATTY. DOCKET NO.</b> TT4314	<b>APPL. NO.</b> 09/976,739
	<b>APPLICANT</b> Christopher L. Wooten, et al.	
	<b>FILING DATE</b> October 11, 2001	<b>GROUP</b> 2623

**U.S. PATENT DOCUMENTS**

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	5,982,920	11/09/99	Tobin, Jr., et al.			

**FOREIGN PATENT DOCUMENTS**

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION

**OTHER DOCUMENTS (Including Author, Title, Date Pertinent Pages, Etc.)**

	Using SSA to Measure the Efficacy of Automated Defect Data Gathering, Kenneth W. Tobin, Shaun S. Gleason, Thomas P. Karnowski, David Guidry, Micro Magazine, April 98, Analysis & Metrology, p.27.
	Spatial Signature Analysis: Rapidly Tracing Semiconductor Defects to Manufacturing Problems, Kenneth W. Tobin, Shaun S. Gleason and Thomas P. Karnowski.
	An Integrated Spatial Signature Analysis and Automatic Defect Classification System, Shaun S. Gleason, Kenneth W. Tobin, Thomas P. Karnowski.

<b>EXAMINER</b>	<b>DATE CONSIDERED</b>
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**EXAMINER:** Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.